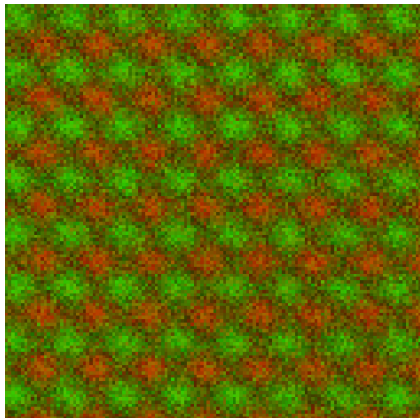


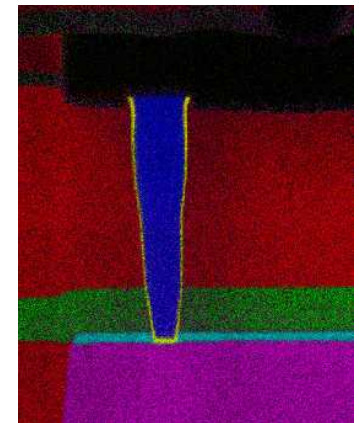
State-of-the-art Analytical Electron Microscopy: 100 times better than before

Paul G. Kotula

Sandia National Laboratories, Albuquerque, NM, USA



- Atomic-resolution x-ray microanalysis
 - Brighter sources
 - Probe correction
 - Efficient x-ray detectors
- Future applications





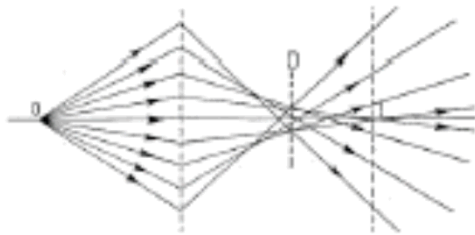
A new paradigm in x-ray microanalysis

- For almost 30 years we have been stuck at about the same point
- Other approaches to high-resolution TEM
 - MeV TEMs (decrease λ), holography (recovers phase and amplitude of the exit wave), focal series exit wave reconstruction, small focal length objective lenses (reduces Cs)
 - In STEM, Cold FEG which gives small source size
- What's changed?
 - Silicon-drift detectors which perform better in all ways than Si(Li) and can be flexibly integrated into the column (-20°C operation)
 - In the past 10 years, aberration correctors coupled with more stable microscope designs
- Simultaneous imaging and x-ray microanalysis at atomic resolution

Motivation of Aberration Correction

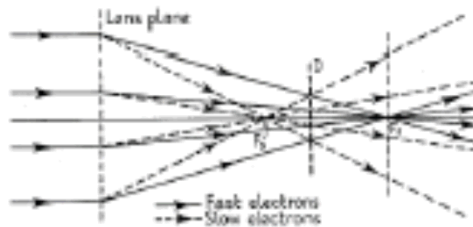
Aberrations

- Spherical

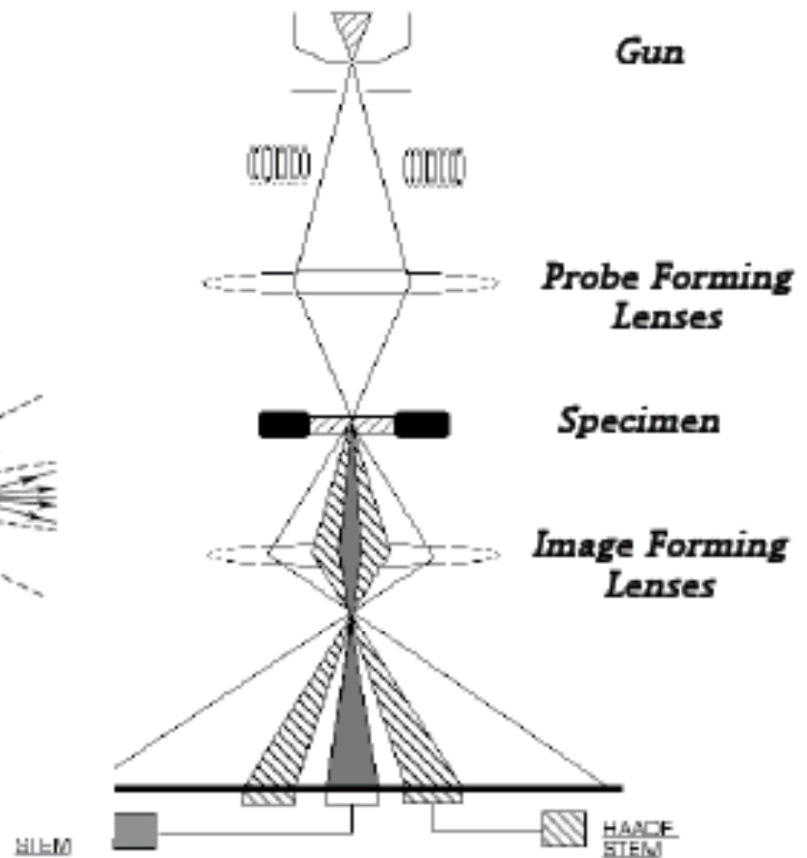


$$r_{sph} = C_s \beta^3$$

- Chromatic



$$r_{chr} = C_c \frac{\Delta E}{E} \beta$$



Courtesy Nestor Zaluzec, ANL

Scherzer's Theorum

O. Scherzer, *Z. Phys.* **101** (1936) 593

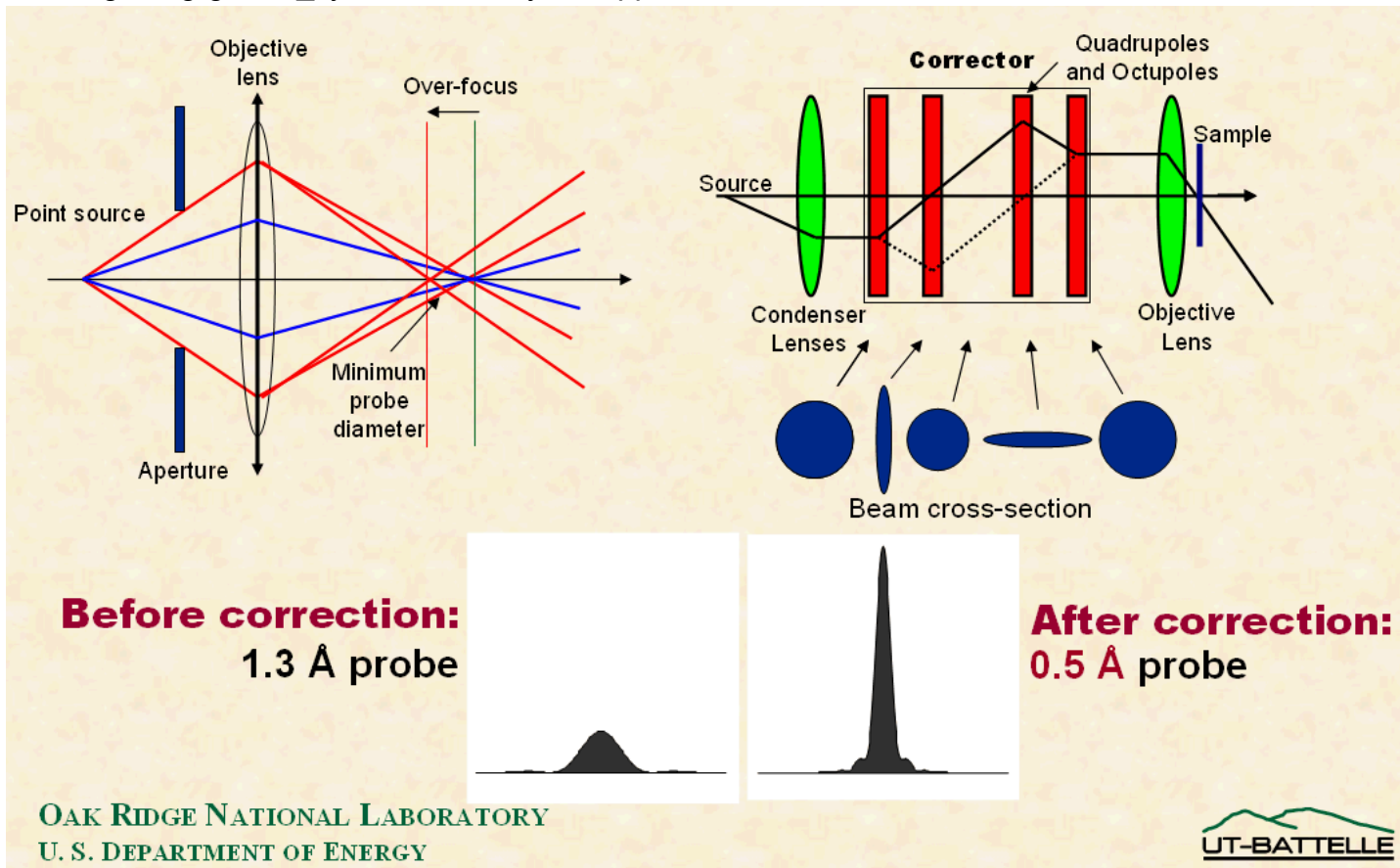
- Electromagnetic lenses with rotational symmetry
 - Suffer unavoidably from chromatic and spherical aberration, C_s is $\sim 1/2$ focal length of the objective lens (immersion geometry) ~ 1 -3 mm



Dodecapole lens used in the DCOR can correct C_s because rotational symmetry has been broken

Aberration Correction in practice

http://www.ornl.gov/~grg/BES_sym/talks/Pennycook.ppt#386,9,2002: NION builds successful STEM aberration corrector



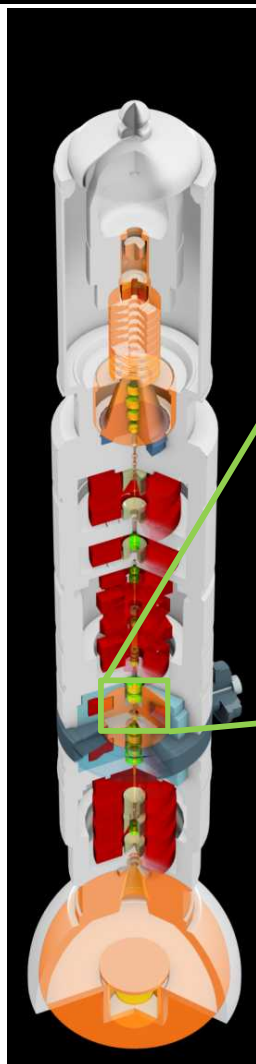
2002 Nion probe corrector, slide from Pennycook, ORNL
Extra non-rotationally symmetric lenses allow correction of Cs and higher order aberrations as well

Atomic resolution x-ray microanalysis

X-FEG

DCOR
(CEOS)

Super-X



Critical elements for atomic resolution x-ray microanalysis

High brightness gun

X-FEG

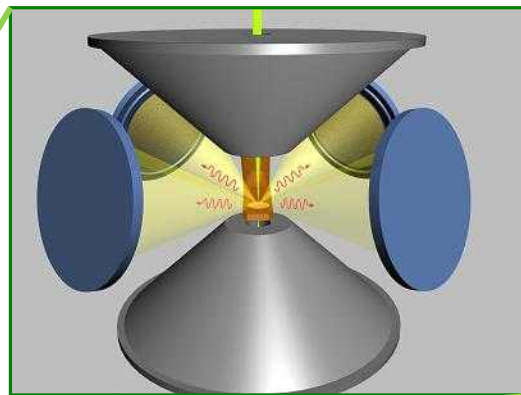
Probe corrector (CEOS-DCOR)

0.08nm @ 200kV

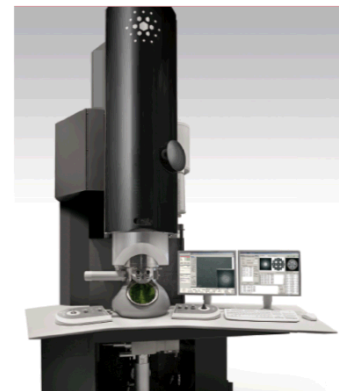
0.12nm @ 80kV

Efficient x-ray detector(s)

SuperX, SDD array



**All of these elements have been integrated on the FEI Titan ChemiSTEM-P (200kV)
SNL has the first one**





New Schottky emitter technology

- New Schottky emitter with the brightness of a cold FEG
- FEI X-FEG brightness increased to $\sim 10^8$ A/sr/m²/ V
 - $\sim 2 \times 10^9$ A/cm²/sr @ 200 kV
 - Comparable to a cold FEG but more stable over time
 - 0.8 eV energy spread
- Probe current (w/o corrector)
 - 0.5 nA in 0.3 nm diameter
 - **Increased by 5x** relative to regular Schottky FEG
- Probe current (with DCOR probe corrector)
 - 200 kV, 1.3 nA in 0.2 nm diameter probe
 - 80 kV, 0.5 nA in 0.2 nm diameter probe

Detector Efficiency: Arrays

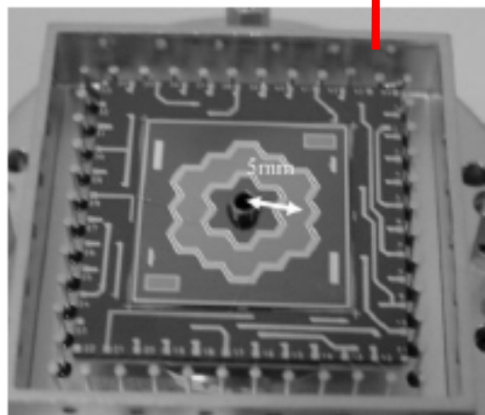
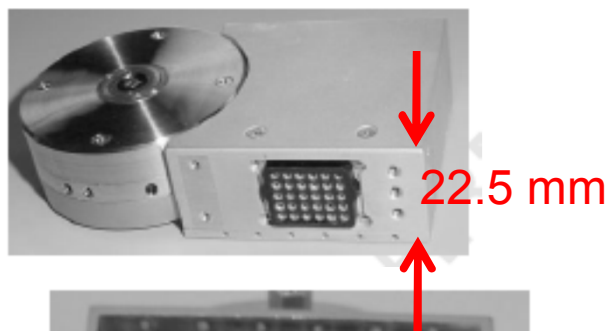
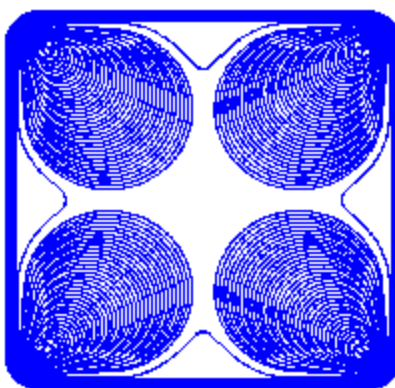
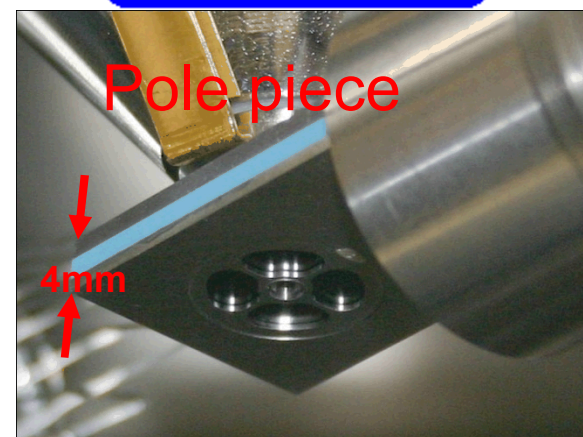
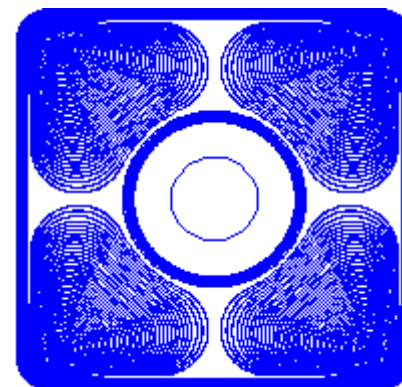


Figure 2. The Ketek 12-element annular SDD chip mounted in its package. The tantalum ion collimator that protects the SDD from scattered protons can be seen protruding through a hole in the center of the chip.

2005 Ketek/Custom imp.
2nd-3rd generation annular
(1.1 sr)



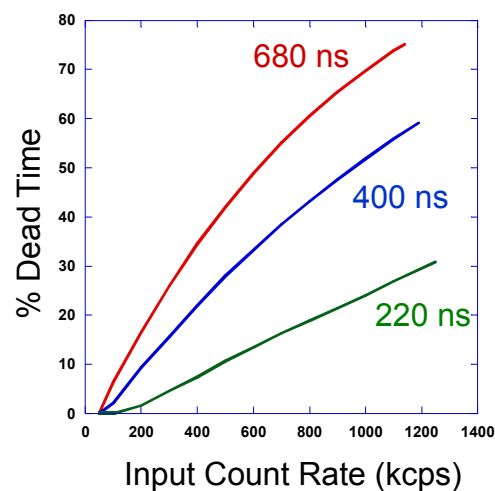
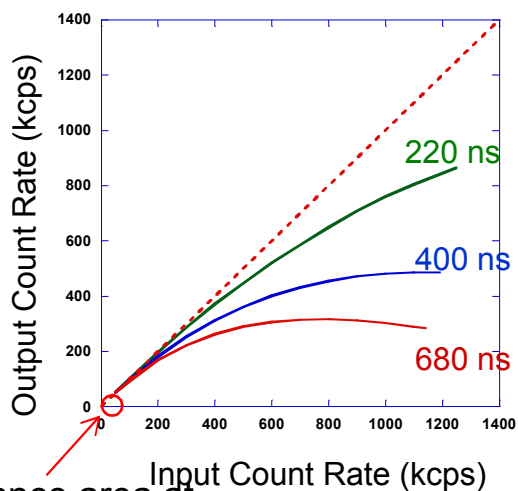
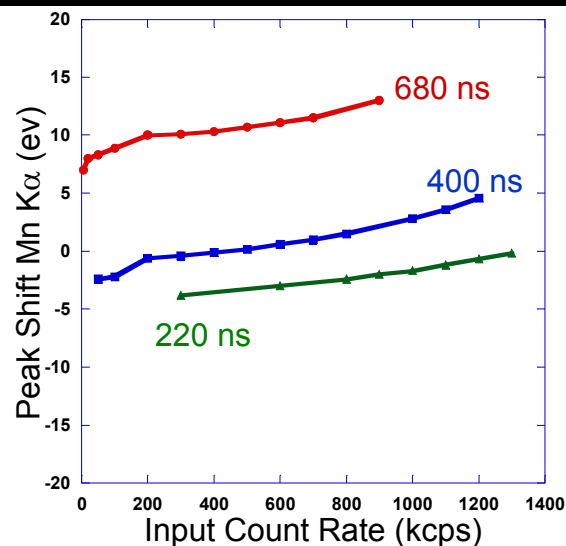
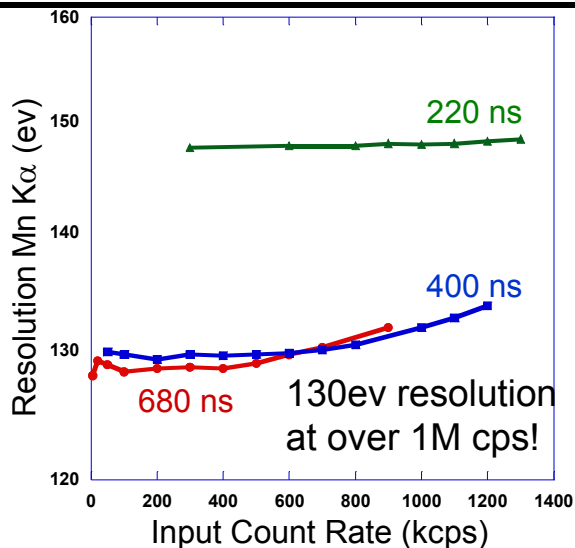
2005 pnSensor/Roentec
4-5th generation
conventional
(40 mm², 0.06 sr)



2007 pnSensor/Bruker
5th generation annular at
SNL(60 mm², 1.1 sr)

5th generation SDD-array performance

SEM data from 4-detectors summed



Si(Li) performance area at
180eV FWHM Mn-K α

Performance superior in every way to Si(Li)

SuperX™: Large solid angle silicon drift detector array provides more flexible AEM integration

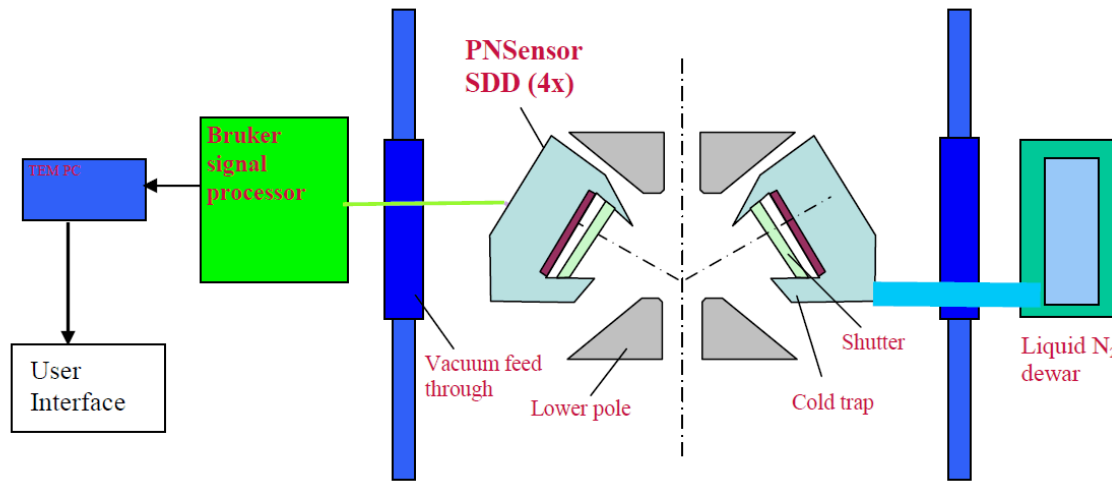
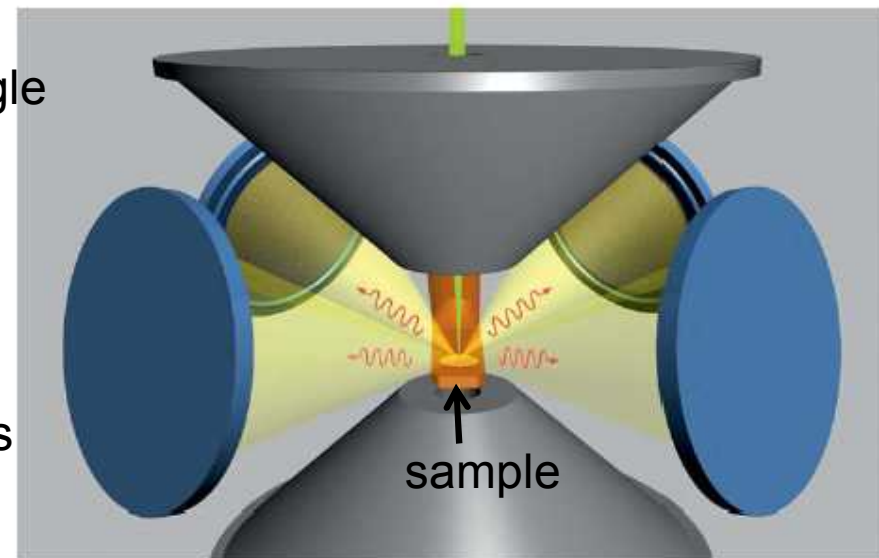


Figure 1. Schematic of Super-X detector

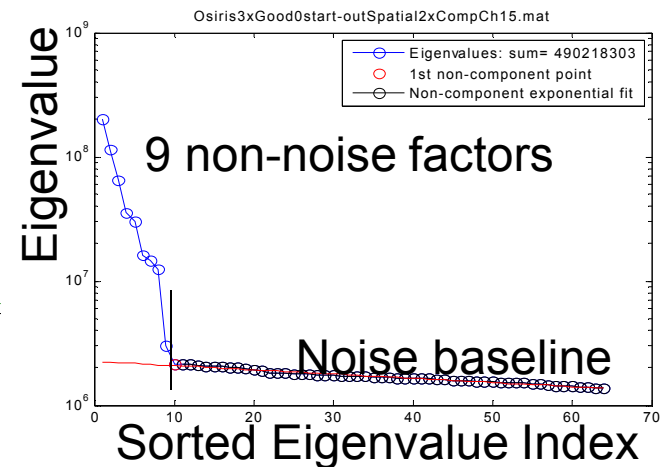
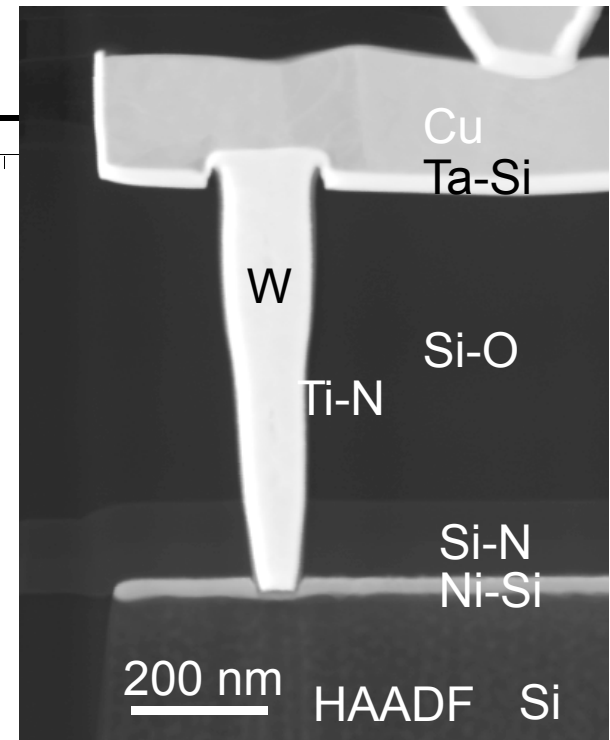
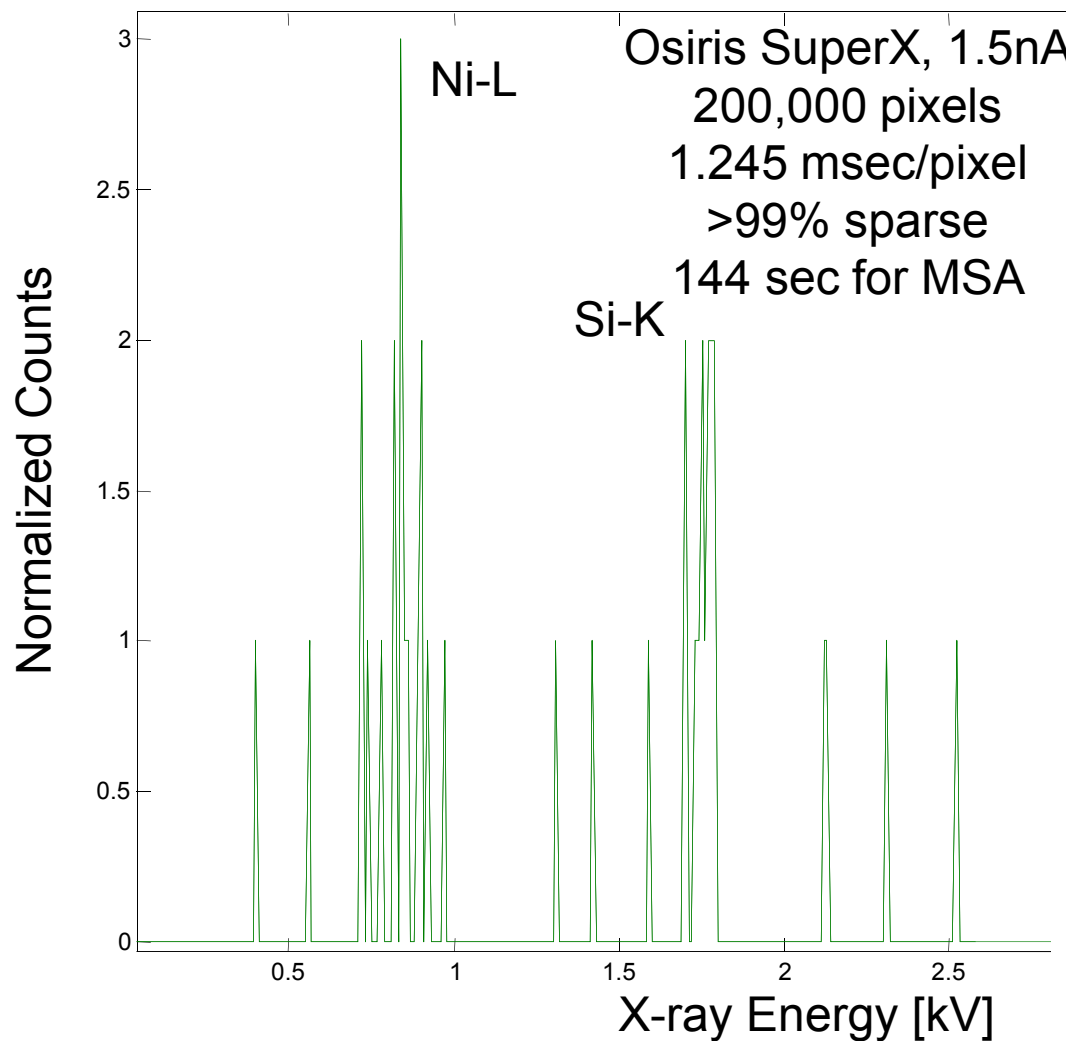
Conceived by FEI with collaboration from Bruker and pnSensor

Revolutionary change in AEM-EDS

- 4-30mm² (120mm²) SDDs with large solid angle
 - 0.9 sr (Osiris-uncorrected)
 - 0.7 sr (Titan-probe corrected)
 - State-of-the-art SDDs
 - Windowless & pnWindow...good light-element performance (C, N, O previously)
 - High-throughput...10 μ sec instantaneous dwell times, multiple pass, drift correction

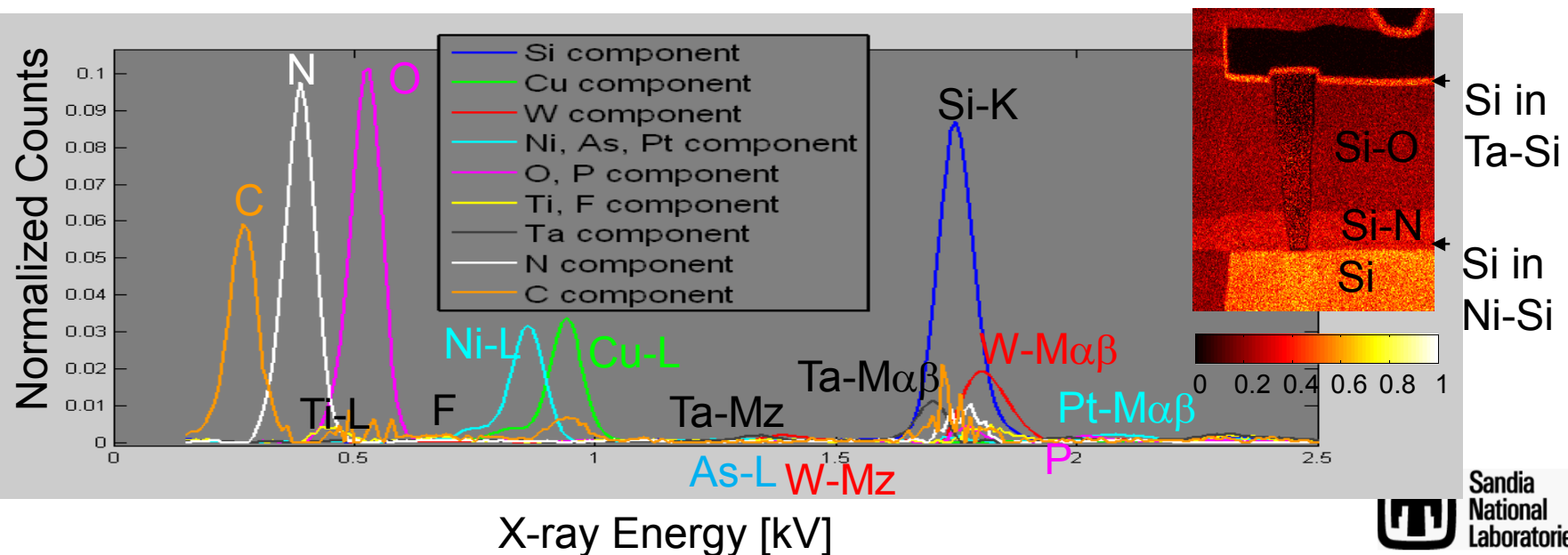
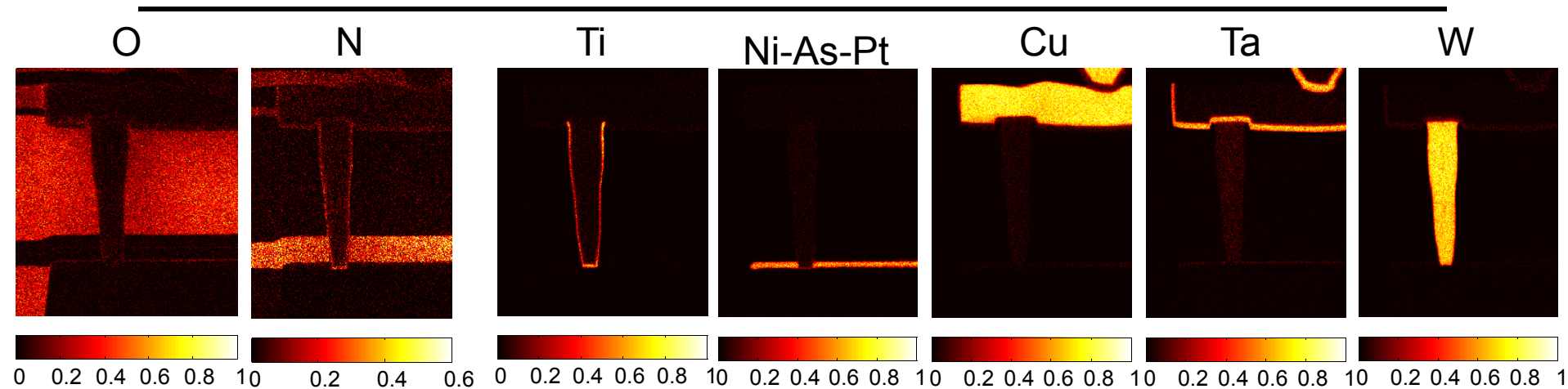


Raw spectrum from the CMOS spectral image



Spectral-Domain Simplicity

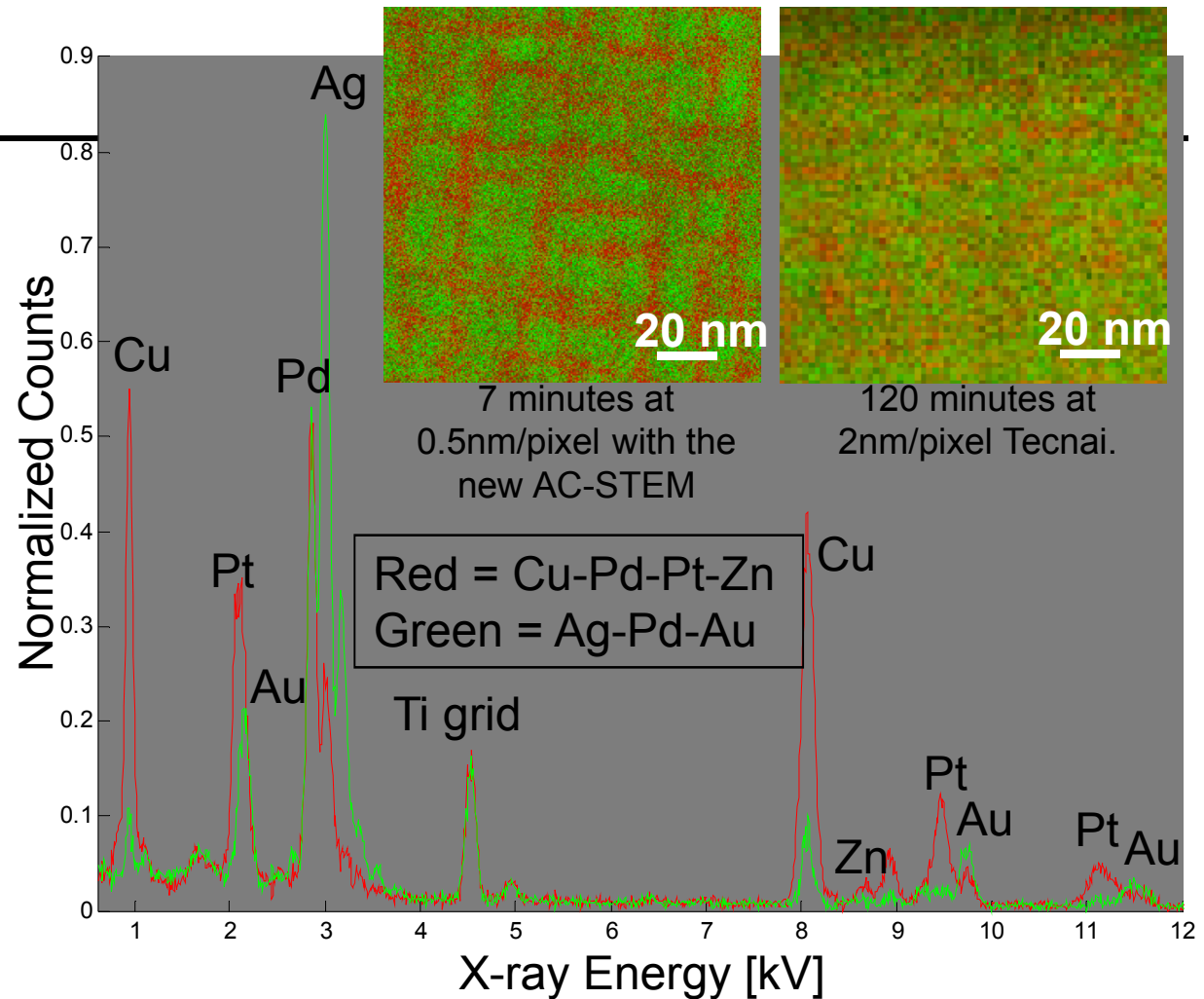
Best Spectral or Elemental 'Contrast'



Medium end analysis

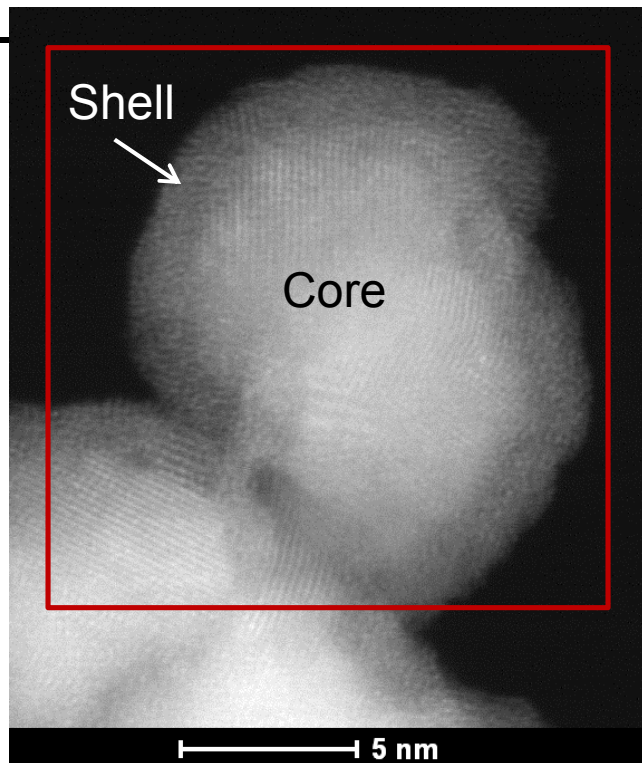
Sub-nm microanalysis of electrical contact materials

Paliney 7, electrical
contact material
nanometer-scale
spinodal decomposition.

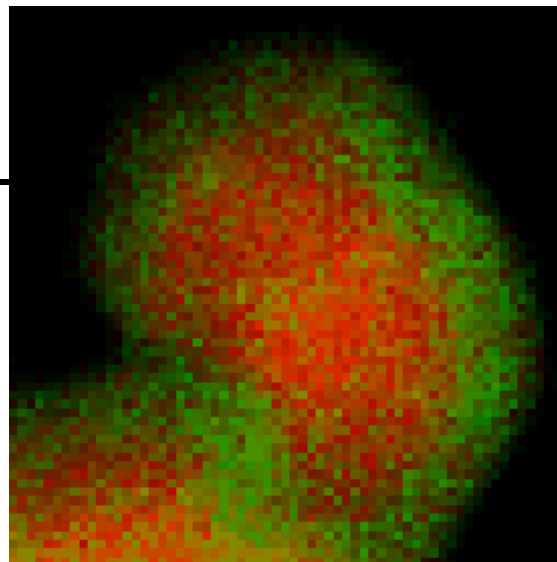


The analytical power of the AC-STEM is *at least 70x* better than the older analytical microscope at Sandia.

Medium end, characterization of hydrogen isotope storage materials

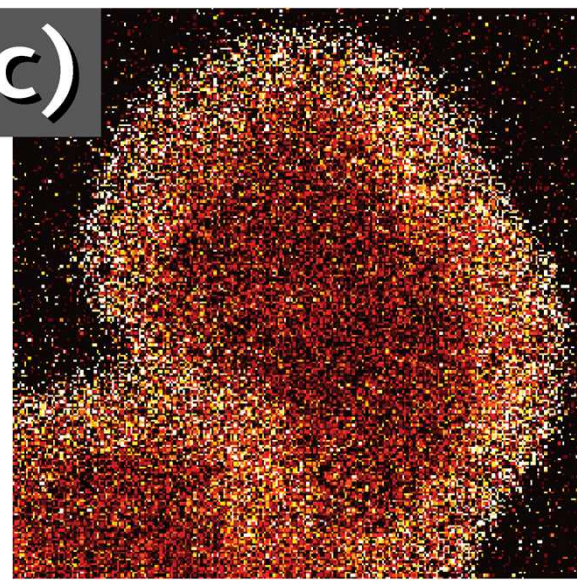


HAADF image



MSA results
Red = Pd-rich core
Green = Rh- and O-rich shell

c)



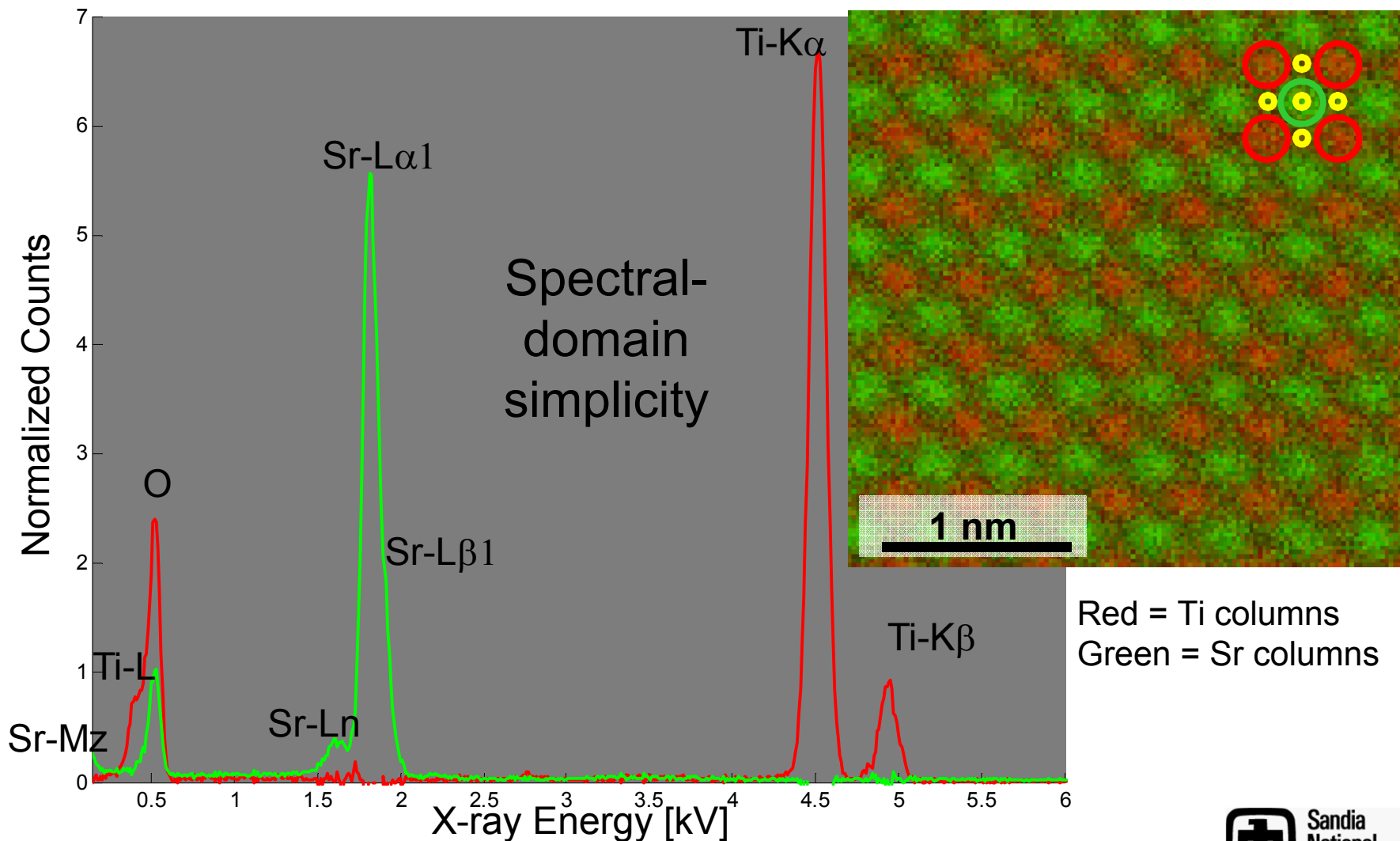
Quantification

Rh at. %
20
15
10
5

16.4 nm

SrTiO₃ [100]

MSA-processed spectral image of SrTiO₃ with no *a priori* information

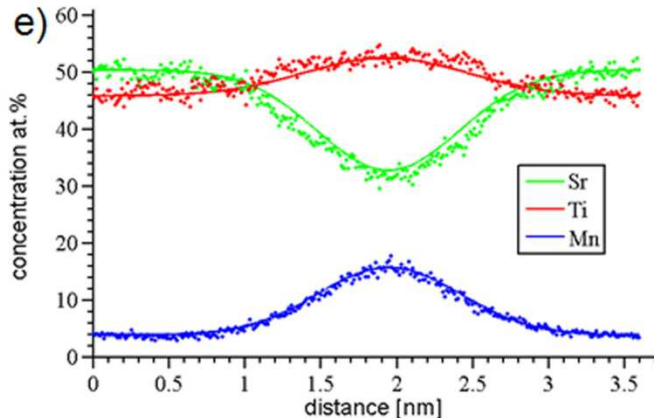
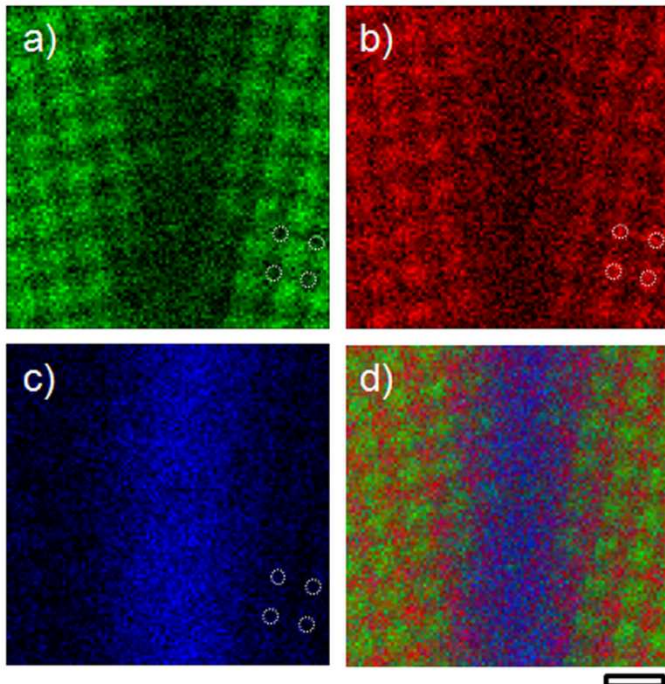


Sr-K lines not shown but correlate with Sr-L

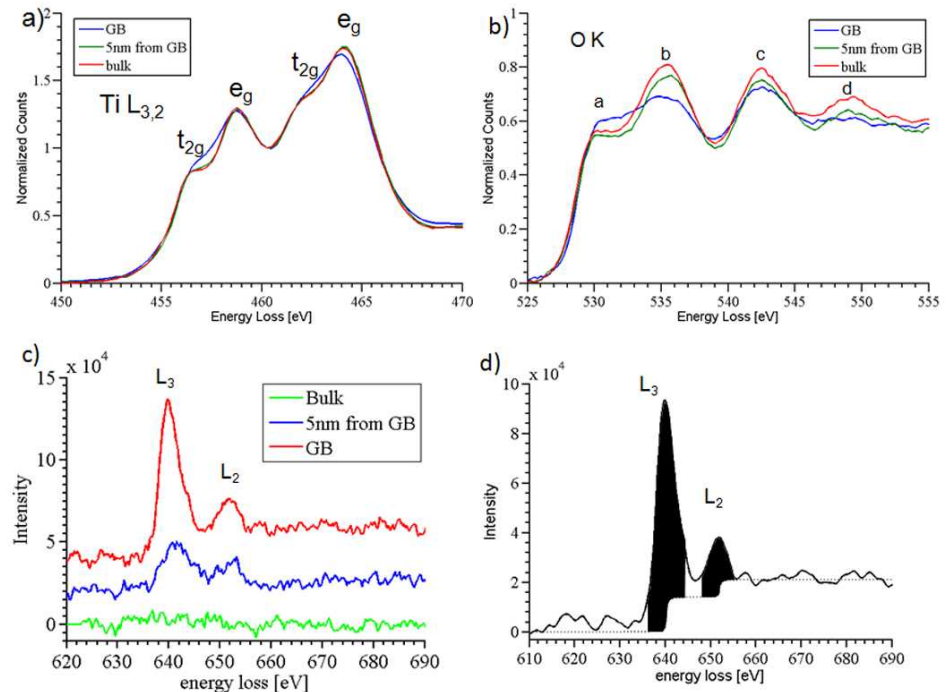
Analysis of Mn-doped STO $\Sigma=13$ Boundaries

$\Sigma 13$ (510)/[001]

Quantitative EDS and EELS

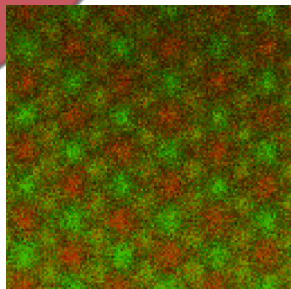
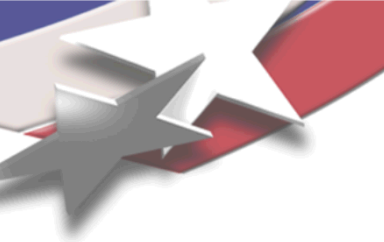


FWTM enrichment at the boundary less than 2nm

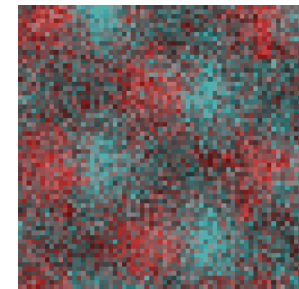
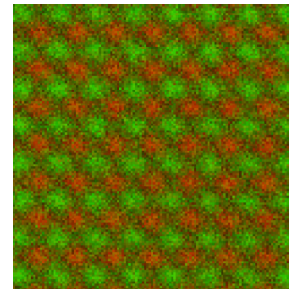


Mn²⁺ at boundary
Mn⁴⁺ in bulk near boundary
(substitutional with Ti)

Hao Yang, Paul G. Kotula, Yukio Sato, Yuichi Ikuhara, Nigel D. Browning. "Segregation of Mn²⁺ Dopants as Interstitials in SrTiO₃ Grain Boundaries," Submitted to APL (2013).



Conclusions



- AEM is undergoing a renaissance with correctors, SDDs, novel diffraction techniques, and better sources.
- Atomic resolution EDS will become more common than EELS. Easier, more elements accessible, esp. heavy ones, more readily quantified
- Novel detector geometries for AEM improve sensitivity and throughput.
- MSA methods are very useful for simplifying the analysis of large, complex data sets (only very simple ones shown today!)
 - Importance of Poisson normalization
 - Factor rotation, spatially or spectrally simple viewpoints
 - Unbiased analysis powerful for materials science, etc. Needle in the haystack....single atoms....
- Quantitative analysis pushed to smaller volumes
 - Understanding the spectrum is critical...every bump matters!
 - Potential for 1000 ppm sensitivity at 0.2 nm?
 - 100 ppm sensitivity at 1 nm?